



FPD Metrology Japan TC Chapter Meeting Summary and Minutes

Japan Standards Spring 2018 Meetings

Monday, May 28, 2018 15:40 – 17:00

SEMI Japan office, Tokyo, Japan

TC Chapter Announcements

Next TC Chapter Meeting

October 2018 (Date and Time to be decided)

SEMI Japan office, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs: Ryoichi Watanabe (Japan Display) / Akira Kawaguchi (Otsuka Electronics)

SEMI Staff: Chie Yanagisawa

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Japan Display	Watanabe	Ryoichi	Sony	Tomioka	Satoshi
KONICA MINOLTA	Nishikawa	Yoshihiro			
Otsuka Electronics	Kawaguchi	Akira	SEMI Japan	Yanagisawa	Chie

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
D31 Revision Task Force	Ryoichi Watanabe (Japan Display)	Not applicable Because the TF was discharged.

Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
D31 Revision Task Force	The task force was discharged.

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
None		

Table 5 Activities Approved by the GCS prior to the Originating TC Chapter meeting

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

Table 6 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

#	SC/TF/WG	Details
None		

Table 7 Authorized Ballots

#	When	TF	Details
None			

Table 8 SNARF(s) Granted a One-Year Extension

#	TF	Title	Expiration Date
None			

Table 9 SNARF(s) Abolished

#	TF	Title
None		

Table 10 Standard(s) to receive Inactive Status

Standard Designation	Title
None	

Table 11 New Action Items

Item #	Assigned to	Details
20180528-01	SEMI Japan staff	To ask SEMI Korea staff who actually attended the FPD metrology Korea TC Chapter meeting held on April 13, 2018, because there are only two attendees recorded on the list of the FPD Metrology Korea TC Chapter meeting minutes held on April 13, 2018 and none of them are the chairs. In addition to that, no SEMI staff name is recorded in the minutes.

Table 12 Previous Meeting Action Items

Item #	Assigned to	Details
none		



1 Welcome, Reminders, and Introductions

Ryoichi Watanabe (Japan Display) called the meeting to order at 15:40. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01_Required_Elements_Reg_20150327_E+J

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: Approve the minutes of the previous meeting held on September 15, 2017 for FPD Metrology part as written.

By / 2nd: Akira Kawaguchi (Otsuka Electronics) / Satoshi Tomioka (Sony)

Discussion: None

Vote: 3 in favor and 0 opposed. **Motion passed.**

Attachment: 02_20170915_FPD-MC&Met_JointMeetingMinutes_Draft_Final

3 Liaison Reports

3.1 FPD Metrology Korea TC Chapter

Chie Yanagisawa (SEMI Japan) reported for the FPD Metrology Korea TC Chapter as attached.

Ryoichi Watanabe (Japan Display) said that there are only two attendees recorded on the list of the FPD Metrology Korea TC Chapter meeting minutes held on April 13, 2018 and none of them are the chairs. In addition to that, no SEMI staff name is recorded in the minutes.

Action Item: 20180528-01: SEMI Japan staff to ask SEMI Korea staff who actually attended the FPD metrology Korea TC Chapter meeting held on April 13, 2018, because there are only two attendees recorded on the list of the FPD Metrology Korea TC Chapter meeting minutes held on April 13, 2018 and none of them are the chairs. In addition to that, no SEMI staff name is recorded in the minutes.

Attachment: 03_KR_FPDM_2018_May

3.2 FPD Metrology Taiwan TC Chapter

Chie Yanagisawa (SEMI Japan) reported for the FPD Metrology Taiwan TC Chapter as attached.

Attachment: 04_FPD TW Liaison Report_201712

3.3 SEMI Staff Report

Chie Yanagisawa (SEMI Japan) gave the SEMI Staff Report as attached. Of note:

- SEMI Global 2018 Calendar of Events
- SEMICON West 2018 Visitor Registration
- Global Standards Meeting Schedule
- 2018 Critical Dates for SEMI Standards Ballots

- A&R Ballot Review
- SEMI Standards Publications
- JRSC Topics
- SEMI Japan e-mail newsletter
- Global Staff Assignment
- Staff Contact - Japan

Attachment: 05_SEMI Staff Report 20180515_0.2

4 Ballot Review

None

5 Subcommittee and Task Force Reports

5.1 D31 Revision Task Force

Ryoichi Watanabe (Japan Display) reported for the D31 Revision Task Force that there has been no activity since SEMI D31-0318 is published. So, he will propose the TF discharge at the New Business section later of this meeting.

6 Old Business

None

7 New Business

7.1 Discharge of D31 Revision Task Force

Ryoichi Watanabe (Japan Display) addressed the committee on this topic.

Motion: To approve the discharge of the D31 Revision TF

By / 2nd: Ryoichi Watanabe (Japan Display) / Satoshi Tomioka (Sony)

Discussion: None

Vote: 3 in favor and 0 oppose. Motion passed.

8 Next Meeting and Adjournment

The next meeting is scheduled for <date> at <event/location>. See <http://www.semi.org/en/events> for the current list of meeting schedules.

Tentatively scheduled in October 2018

Time to be decided

Having no further business, a motion was made to adjourn. Adjournment was at 17:00.



Respectfully submitted by:

Chie Yanagisawa

Manager

SEMI Japan

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Minutes tentatively approved by:

Ryoichi Watanabe (Japan Display), Co-chair	January 16, 2019
Akira Kawaguchi (Otsuka Electronics), Co-chair	January 16, 2019

Table 13 Index of Available Attachments^{#1}

<i>Title</i>	<i>Title</i>
01_Required_Elements_Reg_20150327_E+J	04_FPD TW Liaison Report_201712
02_20170915_FPD-MC&Met_JointMeetingMinutes_Draft_Final	05_SEMI Staff Report 20180515_0.2
03_KR_FPDM_2018_May	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.